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## **U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-2002/0193899 A1	12-2002	Shanmugasundram et al.	700/108
	В	US-6,587,744 B1	07-2003	Stoddard et al.	700/121
	O	US-6,584,369 B2	06-2003	Patel et al.	700/100
	D	US-6,594,536 B1	07-2003	Lin et al.	700/99
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	К	US-			
	L	US-			
	М	US-			

## FOREIGN PATENT DOCUMENTS

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## **NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)				
	U	"Cycle time advantages of mini batch manufacturing integrated metrology in a 300 mm vertical furnace". Noben et al. Semiconductor Manufacturing Symposium, 2001 International. San Jose Ca. 10/08/01-10/10/01, Pages 411-414.				
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).) Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.